

**NC-2000FLA FULLY-AUTO RESISTIVITY & FLATNESS MEASUREMENT AND SORT SYSTEM**

**NC-2000FLA**



- Fully automatic resistivity & flatness measurement system with robot transfer sorting system
- Multi-point, Non-Contact Type using Eddy current method
- Resistivity, Flatness (thickness) and conductivity (P/N) measurements
- Number of cassette station can be customized on request
- Electrical capacitance method for wafer thickness
- Temperature correction for silicon wafer function
- Measure Range depends on selected Probe type
- Sample Size (∅): 3" to 8"

MEASURE RANGE				
PARAMETER	LOW PROBE TYPE	MIDDLE PROBE TYPE	HIGH PROBE TYPE	S-HIGH PROBE TYPE
RESISTIVITY (Ω.cm)	0.001 to 0.05	0.05 to 0.5	0.5 to 60.0	60.0 to 200.0
SHEET RESISTANCE (Ω/Sq)	0.01 to 0.5	0.5 to 10.0	10.0 to 1k	1k to 3k

